

## **Search Notes**



Application/Control No.

**Applicant(s)/Patent under  
Reexamination**

10/791.067

FENG. KAI DI

**Examiner**

## Art Unit

Ernest F. Karlsen

2829

SEARCHED

Class	Subclass	Date	Examiner
	763		
	501		
324	752	4/28/2005	324
	765		
	767		
714	733	4/28/2005	324
	734		

**SEARCH NOTES  
(INCLUDING SEARCH STRATEGY)**

DATE EXMR

test same (wafer or die or ch.p) same  
optical and (photo adj detector or  
photodetector)

4:28:2005

## INTERFERENCE SEARCHED

Class      Subclass      Date      Examiner